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To: Commissioner of Patents and Trademarks

Washington, D.C. 20231

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Subject:

Serial No. 09/945,436 09/04/01

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A METHOD FOR MAKING HIGH-PERFORMANCE RF INTEGRATED CIRCUITS

Grp. Art Unit: 2832

## INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56. Copies of each document is included herewith.

U.S. Patent 6,046,101 to Dass et al., "Passivation Technology Combining Improved Adhesion in Passivation and a Scribe Street Without Passivation", discloses a process where passivation is not formed over some scribe streets.

- U.S. Patent 5,904,546 to Wood et al., "Method and Apparatus for Dicing Semiconductor Wafers," discloses a dicing process on scribe lines to form planar inductors.
- U.S. Patent 6,043,109 to Yang et al., "Method of Fabricating Wafer-Level Package," discloses a IC process (including inductors) where wafers are sawed on scribe lines.
- U.S. Patent 5,387,551 to Mizoguchi et al., "Method of Manufacturing Flat Inductance Element," discloses an inductor process and dicing process.

Sincerely

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